

ABSTRACT

There is disclosed a piezoelectric/electrostrictive film type actuator (11) which comprises a ceramic substrate (44), and a piezoelectric/electrostrictive device (78) disposed on the ceramic substrate (44) and being provide with a piezoelectric/electrostrictive film (79) and electrode film (73, 75, 77); the device being driven by displacement of the piezoelectric/electrostrictive device (78); and the piezoelectric/electrostrictive device (78) wherein the piezoelectric/electrostrictive film (79) and electrode film (73, 75, 77) are alternately laminated to form the electrode from a uppermost layer and a lowermost layer possesses a plurality of layers of piezoelectric/electrostrictive films (79). The piezoelectric/electrostrictive film type actuator is superior in that it can easily highly be integrated without including a structure laminated using an adhesive, and attain a larger displacement with the same driving voltage, a fast response speed and a large generation force.